

-

(2003/11/1 2003/9/22)

(MPS – Device) – –
(-) (PC)

.(V_B) (V_T)

(-)

(-)

Characteristics Study of the Insulator Polycarbonate Metal-Polymer-Semiconductor Device

Ahmed N. Al-Watani

Physics Department

College of Science

Mosul University

ABSTRACT

In this work, Metal-Polymer-semiconductor devices (MPS-Devices) have been fabricated using a thin film of Poly carbonate (PC). From characterization of the devices, threshold voltage (V_T) and breakdown voltage (V_B) were determined. The effect of Polymer films thickness and the temperature on the (V_T) and (V_B) were studied. The results show that both voltages increase with increasing Polymer film thickness and decrease with the temperature. Illuminated (I-V) characteristics of the fabricated device

were studied also, it was clear that the current and voltage increases with increasing illuminated intensity, while (V_T) decrease with increasing illumination intensity. Finally the (C-V) characteristics was studied, the results showed that there are change in the capacity with change a voltage within range, out of this range the capacity fixed and the capacity of the device increases with increasing the frequency at same value of voltage.

...

.(2001) (2001) (Gerstenberg, 1970)

(Little, 1994) (Nicholas, 1983)

.(Sakai et al., 1988) (Ohan et al., 1991)

)

.(1999

(950 A°)

...

- -

(MPS-Devices)

(V_T)

(-)

(V_B)

(V_B)

(V_T)

(-)

:

(1000 A°)

(PC)

(4000)

(Print Motor Type UGPMEE.09.PM12)

(FARNEEL)

(1 Amp)

(30 Volt)

(5:1)

(3905 A°, 2800 A°, 1900 A°, 980 A°)

(Tolansky Tech.)

:

(MPS-Devices)

- -

(P-Tyep)

[(1.5- 4) Ω.cm]

(Si [100])

(1x1) cm

[450 cm²/V.sec]

(HF, 4:10)

(99.999%)

.(Edwards Coating Unit Model 6E4)

$$\begin{aligned}
 & \text{:(} - \text{)} \quad .1 \\
 & \text{: (} - \text{)} \quad . \\
 & - \quad - \quad (- \text{)} \quad (1) \\
 & \quad \quad \quad \text{(PC)} \\
 & (- \text{)} \quad (3905 \text{ A}^\circ, 2800 \text{ A}^\circ, 1900 \text{ A}^\circ, 980 \text{ A}^\circ) \\
 & \text{.(Schotkey Diode)}
 \end{aligned}$$

$$\begin{aligned}
 & \text{(V<4 Volt)} \\
 & \text{[(V}_T \text{)]}
 \end{aligned}$$

(V>4 Volt) .(Sze, 1990) (Maissel and Glang, 1969)

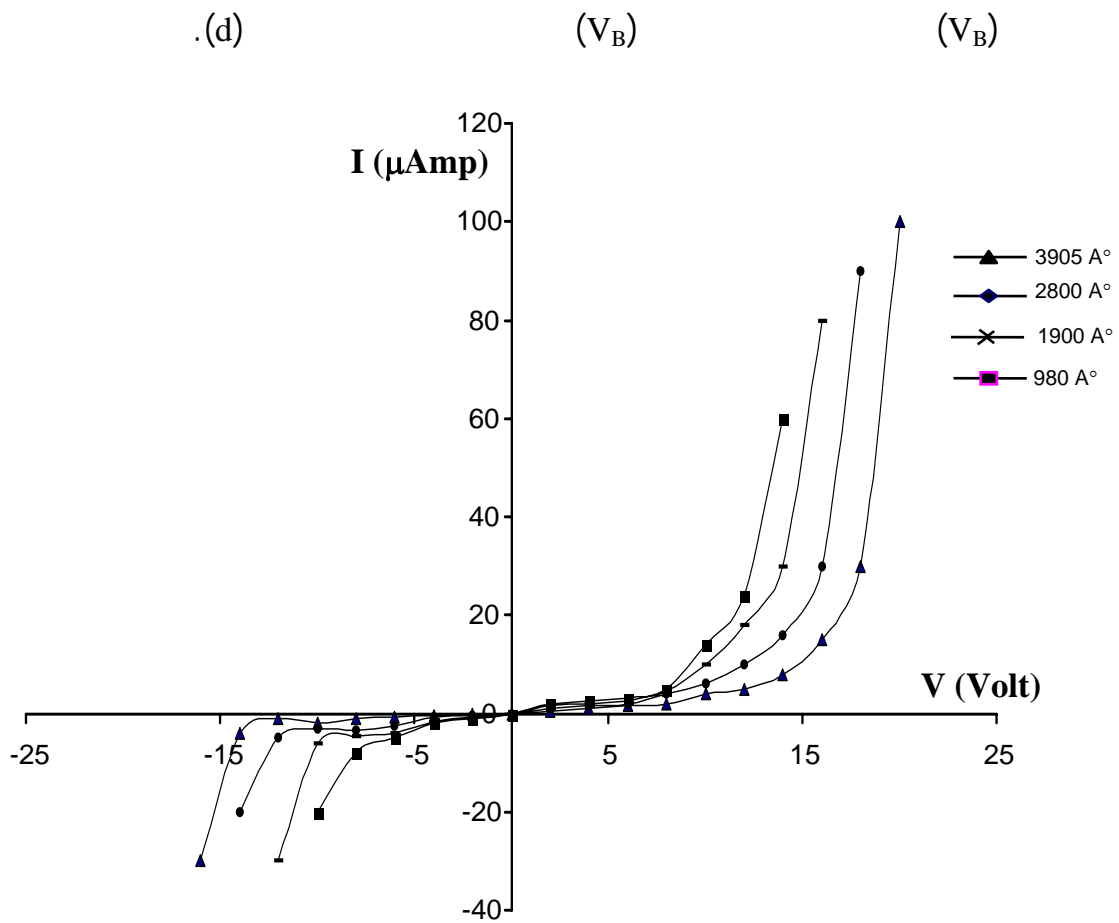
(2000)

$$\text{[(V}_T \text{)]}$$

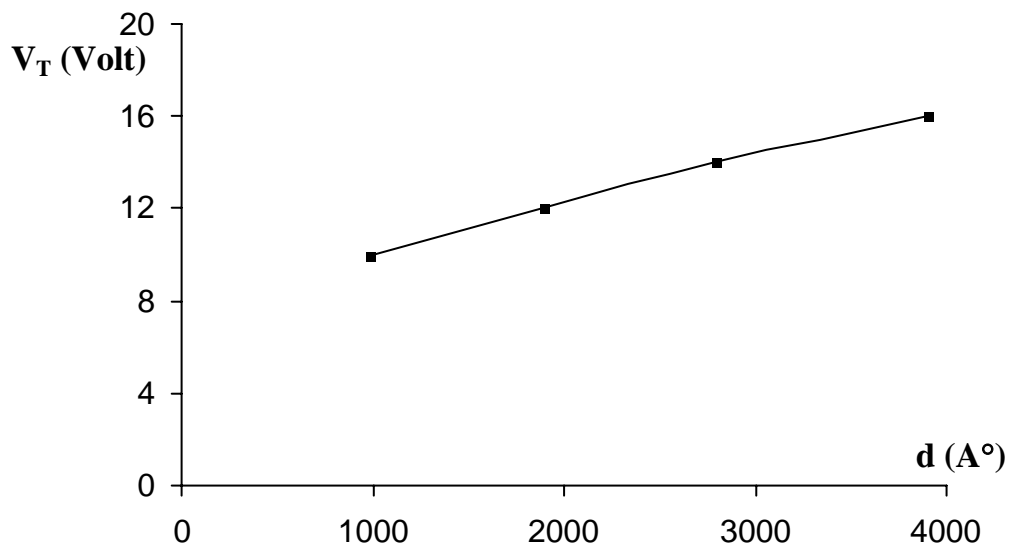
$$\text{[(V}_B \text{)]}$$

(2) .(d) (V_T)

...



(I-V) :1



:2

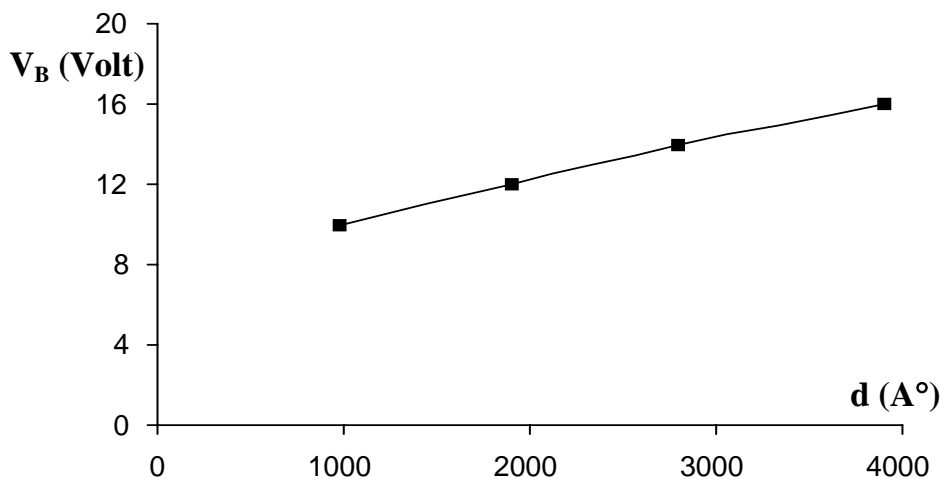
(3)

:(1)

$$J = \left[\frac{9}{8} \right] \epsilon \mu \frac{v^2}{d^3} \tag{1}$$

:

$$\begin{aligned} &= \epsilon & &= J \\ &= v & &= \mu \\ & & &= d \end{aligned}$$



:3

: (-)
- - (I-V) (4)

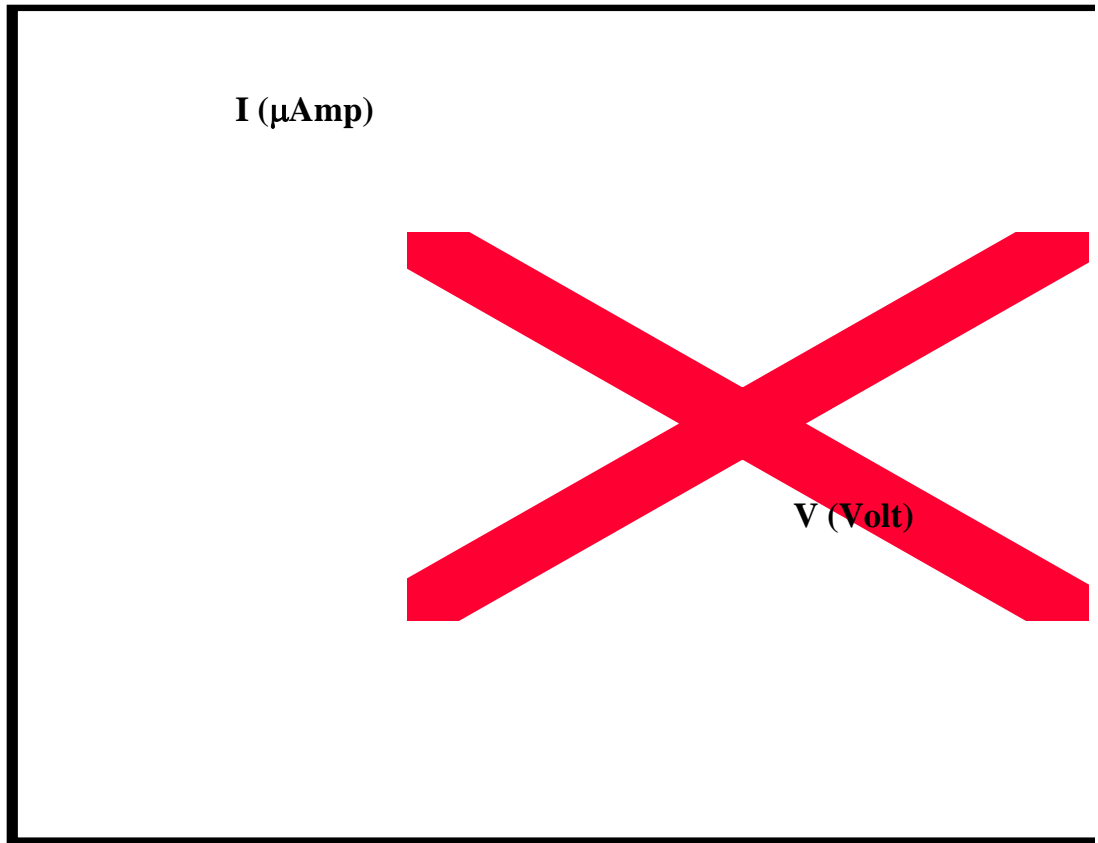
(20 C° - 80 C°) (1900 A°)

(5)

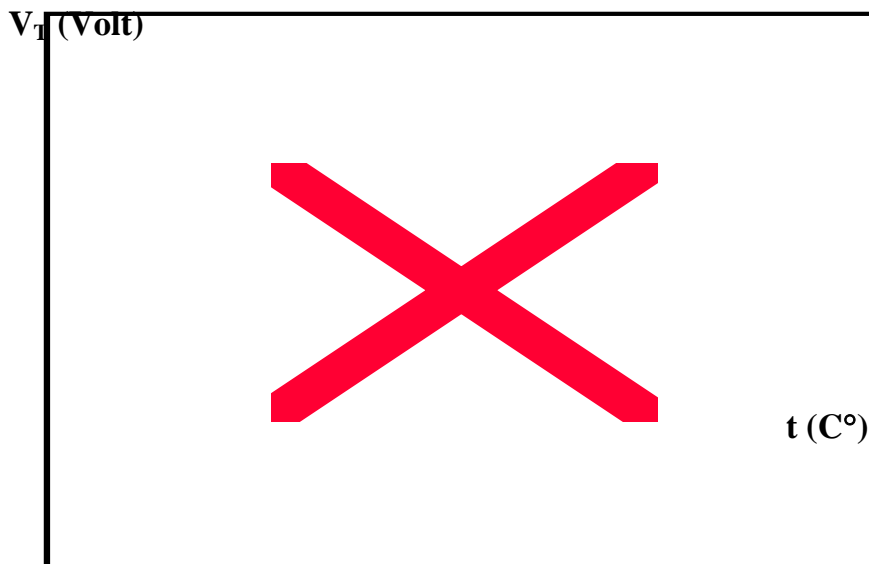
(V_T) (I-V) (V_T)

(6) (V_B)

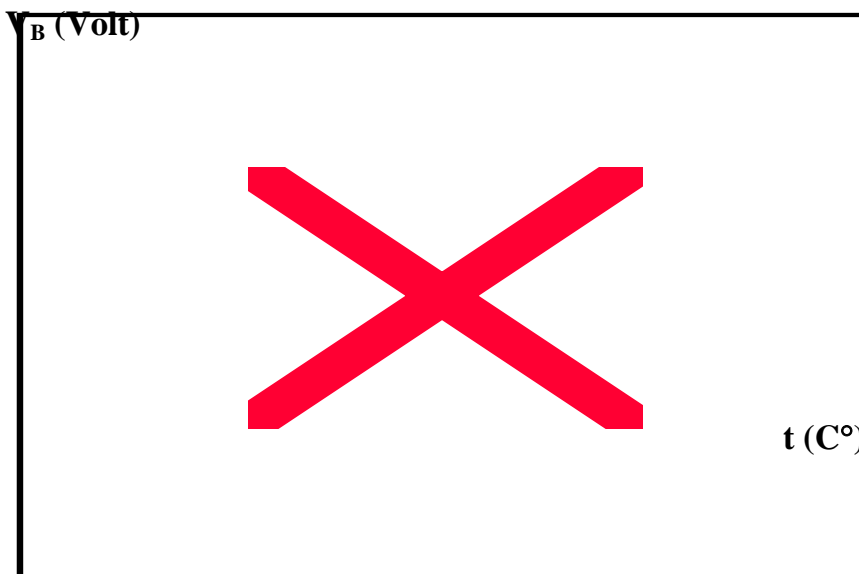
...



(I-V) :4



(V_T) :5



(V_B) :6

:

.1

.(Nicholas and Versnon, 1966)

.2

(3905 A°, 2800 A°, 980 A°)

.1900 A°

: (-)

- - (I-V) (7)

(I-V)

.(20 C°)

1900 A°

(I-V)

()

.(50 mW/cm²) (20 mW/cm²)

(V_T)

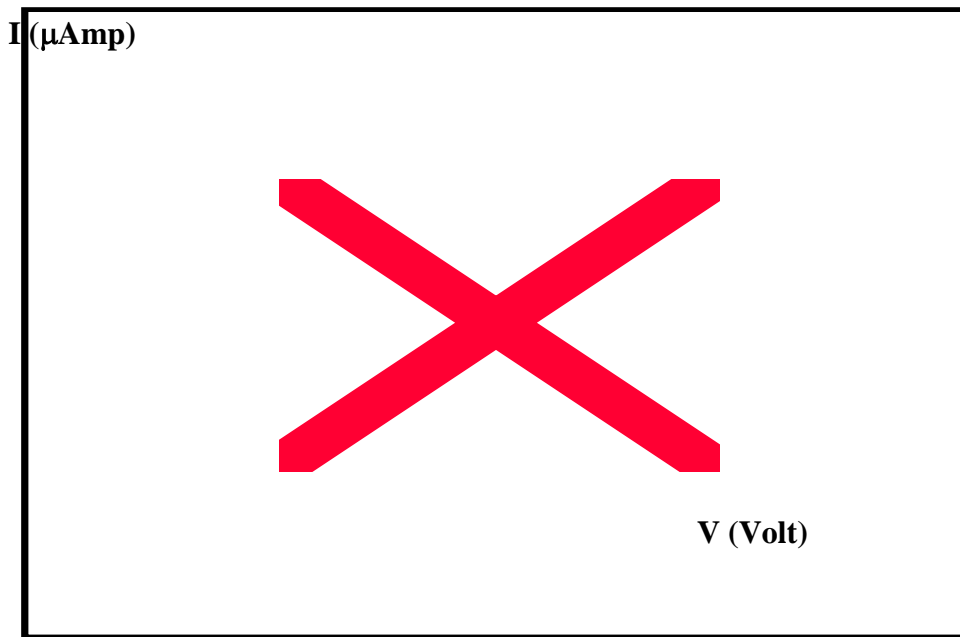
() -

:(2) (Panakove, 1971) (V_T)

$$\sigma = n e \mu \exp[-E_a / K_B T] \quad (2)$$

:

	= n	= μ
	= K_B	= E_a
	= T	= μ



(I-V) :7

:(-) .2

- - (-) (8)

.(1900 A°)

(V >12 Volt)

(V > 12 Volt)

.(10 Hz)

.(Buchanan, 1999)

(1000 Hz 100 Hz)

.(8)

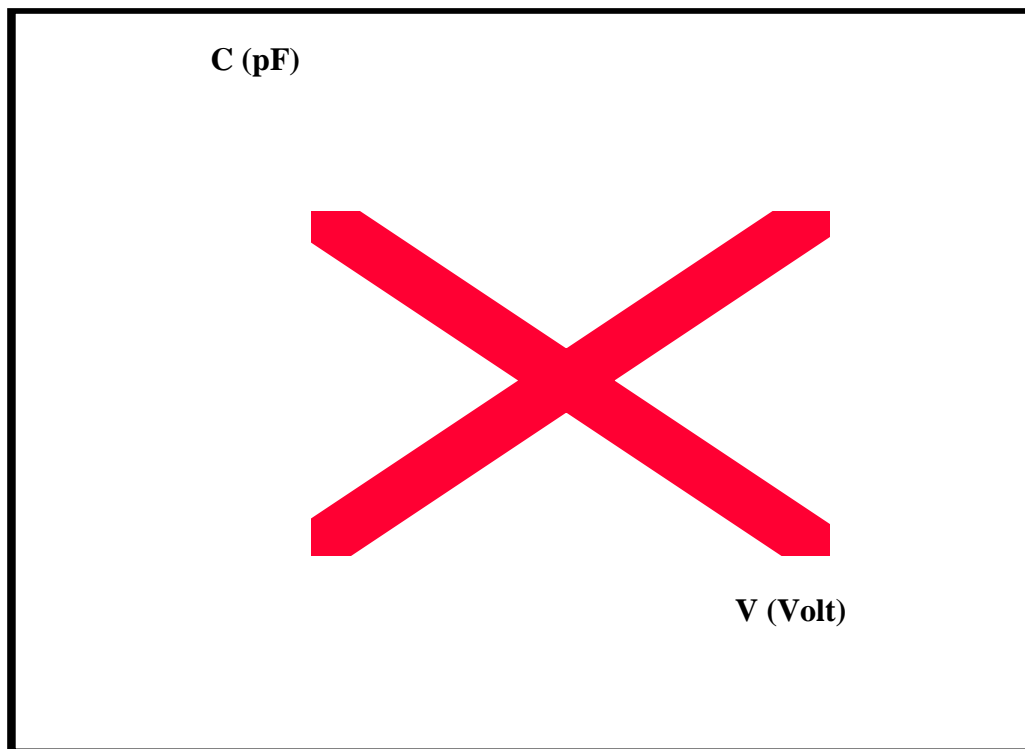
.(Dornecke, 2001)

:(3)

$$C = \epsilon \frac{A}{d}$$

(3)

:
= ε
= A
= d



: 8

				.1
		(V _B)	(V _T)	.2
		(V _B)	(V _T)	.3
				.4
				.5
				.6
	"	"		.7
				.8
			.2000	
12	(PMMA)			
			.110-102	1
			.1999	
11			.2001	
			.115-107	3
			.2001	
		.189-184	4	12

Buchanan, D.A., 1999. Selecting the gate dielectric: Materials Integration and Reliability
IBM. Journal of Research and development, Vol. 45, 245, pp. 2-8.

Dorneke, B.M., 2001, Selecting and Applying Film capacitors, Electronic News, Vol.47,
38, pp. 1-9.

Gerstenberg, D., 1970. Hand book of Thin Film Technology, Edited by L.I. Maissd and
R.Glang, McGraw Hill, New York.

Little, W.A., 1994. Phys. Rev., Vol.134,pp. 1416-1420.

Maissel, L.I. and Glang, R., 1969. Hand book of Thin Film Technology. International
Business Machines Cooperation, Edited by L.I. Maissd and R.Glang, McGraw Hill,
New York

Nicholas, A.N., 1983. Polymer News, Vol. 8, pp. 225-226.

Nicholas, K.G. and Verson, E.V., 1966. Transistor Physics. Champman and Hall Ltd.

- Ohan, O.Z.; Msnssur, H.L. and Habobe, N.F., 1991. Electrical Properties of Polye Styrene-(Anthraquinone copolymer) Thin Film, AL- Mustansiriya Journal of Sciences, Vol.4, No.1, pp. 78-82.
- Pankove, J.I., 1971. Optical Processes in Semiconductors. General Publishing Company Ltd., Canada, U.S.A.: 307-310.
- Sakai, K.; Matsuda, H.; Kawada, H.; Eguchi, K. and Nakagiri, T., 1988. Switching and Memory Phenomena in Langmuir- Blodgett Films, Appl. Phys. Lett., Vol. 53, No.14, pp. 1274-1276.
- Sze, S.M., 1990. Semiconductor Devices Physics and Technology, John Wiley, New York.